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Stalson

PATENT Attorney Docket No. 07553.0065

Customer Number: 22,852

## **AMENDMENTS TO THE SPECIFICATION:**

Please amend the specification as follows:

Add the following new paragraph after the title at page 1:

## CROSS REFERENCE TO RELATED APPLICATIONS

This application is a National Phase Application of International Application

Number PCT/JP2005/003609, filed March 3, 2005, and claims the priority of Japanese

Patent Application No. 2004-063228, filed March 5, 2004, the content of both of which is incorporated herein by reference.

Please amend the first full paragraph, at page 3, line 18 to page 4, line 12 as 121

However, in recent years, in accordance with sophistication of functions and speed increase of an integrated circuit, a wiring structure has rapidly become more microscopic and thinner and a wiring layer has become extremely thin, and therefore, giving a stylus pressure to a <u>the</u> probe for the inspection as described in the conventional patent document 1 involves a risk of damaging a wiring layer and an insulation layer because the probe penetrates not only the oxide film but also the wiring layer or because of a concentration stress from the probe. On the contrary, decreasing the stylus pressure involves a risk of causing unstable continuity between a <u>the</u> probe and <u>an the</u> electrode pad. Further, though the bumps described in the patent documents 2, 3 can surely break <u>an the</u> oxide film of an electrode pad by the